

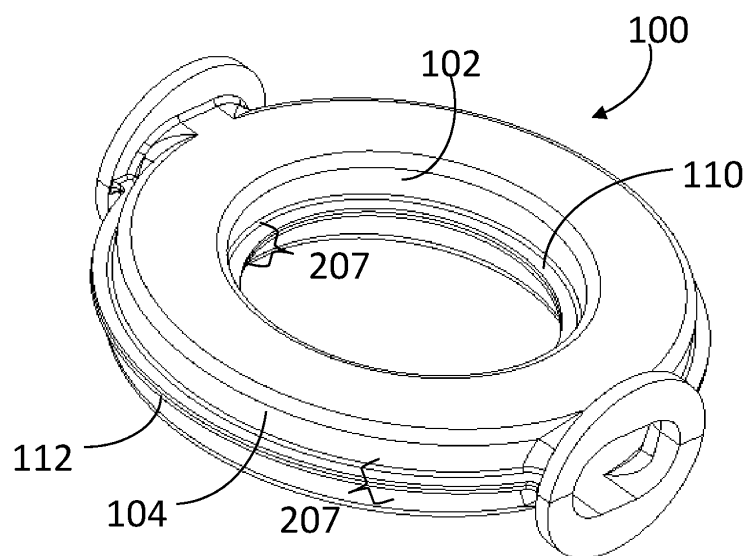


FIG. 1

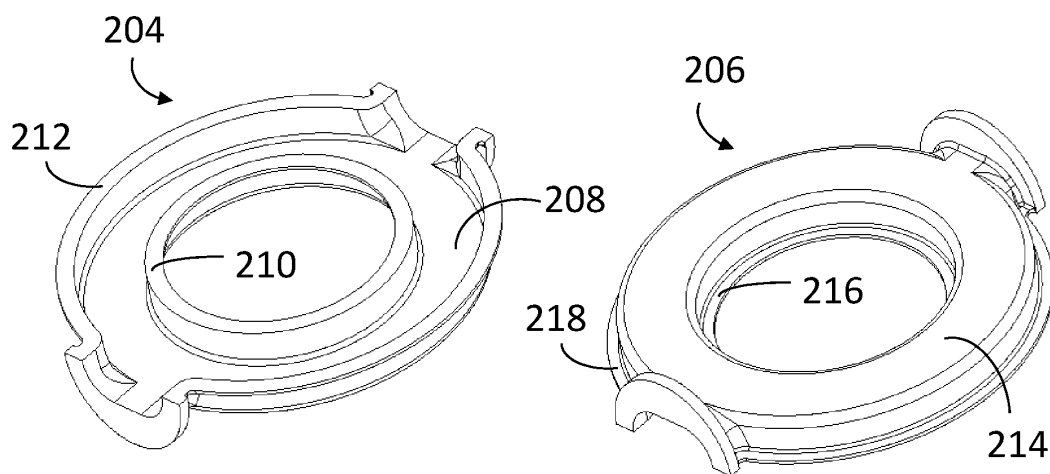


FIG. 2

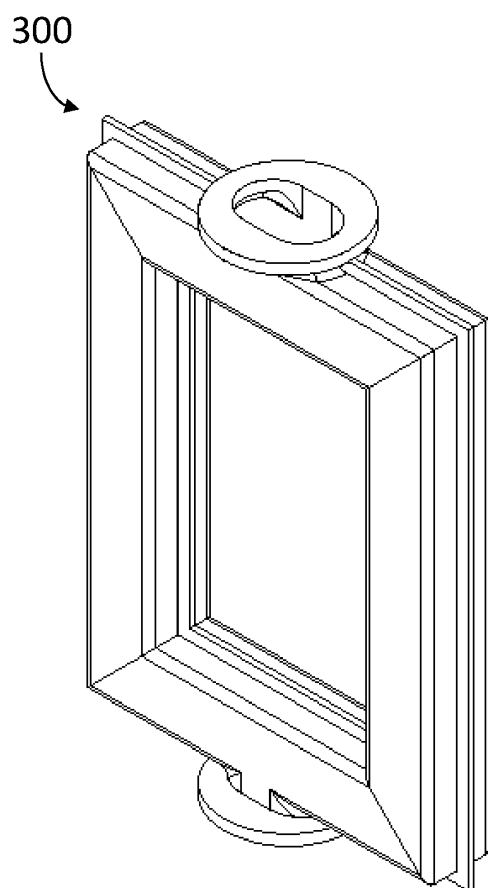


FIG. 3

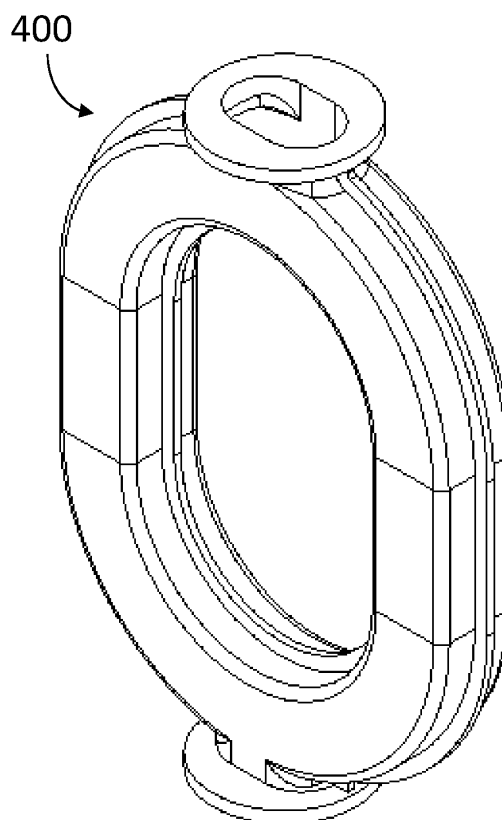
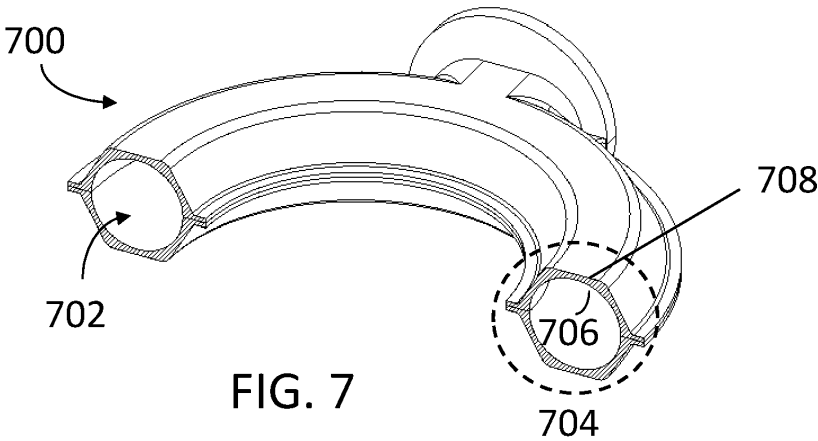
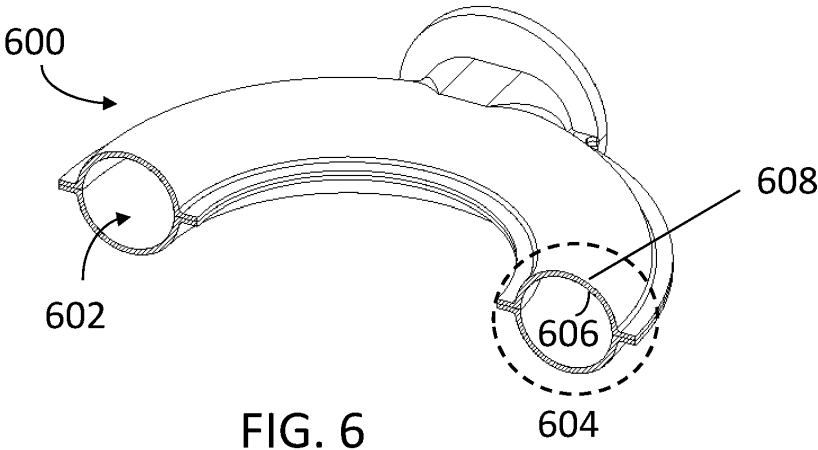
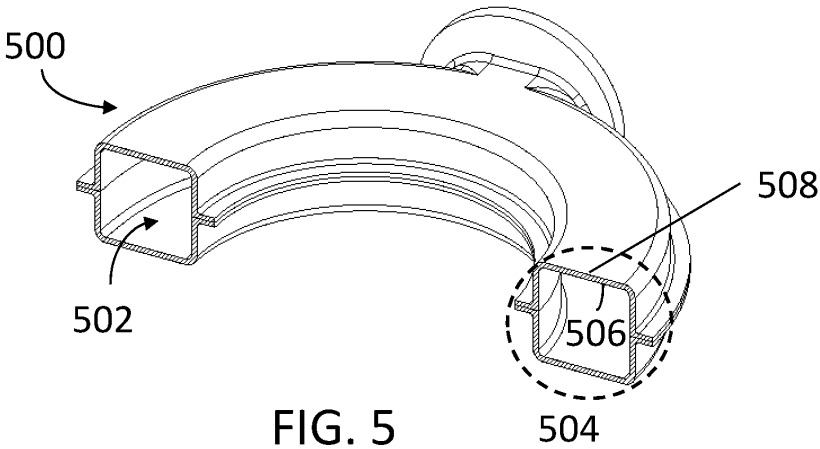


FIG. 4



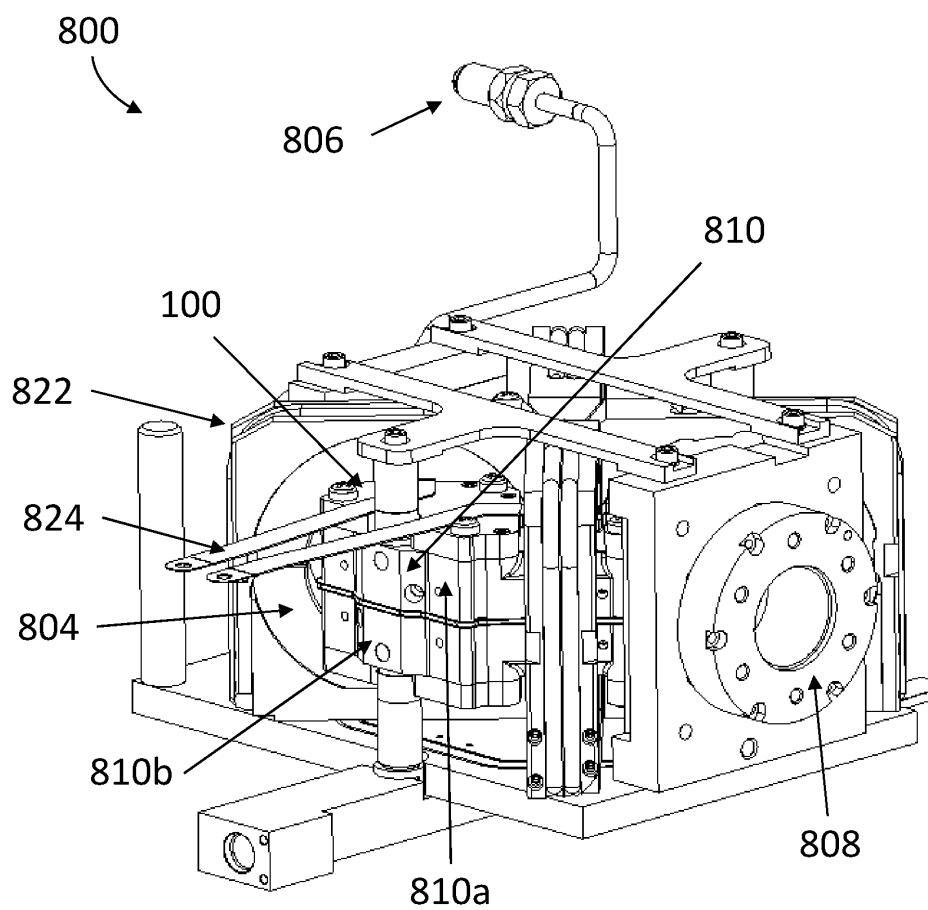


FIG. 8A

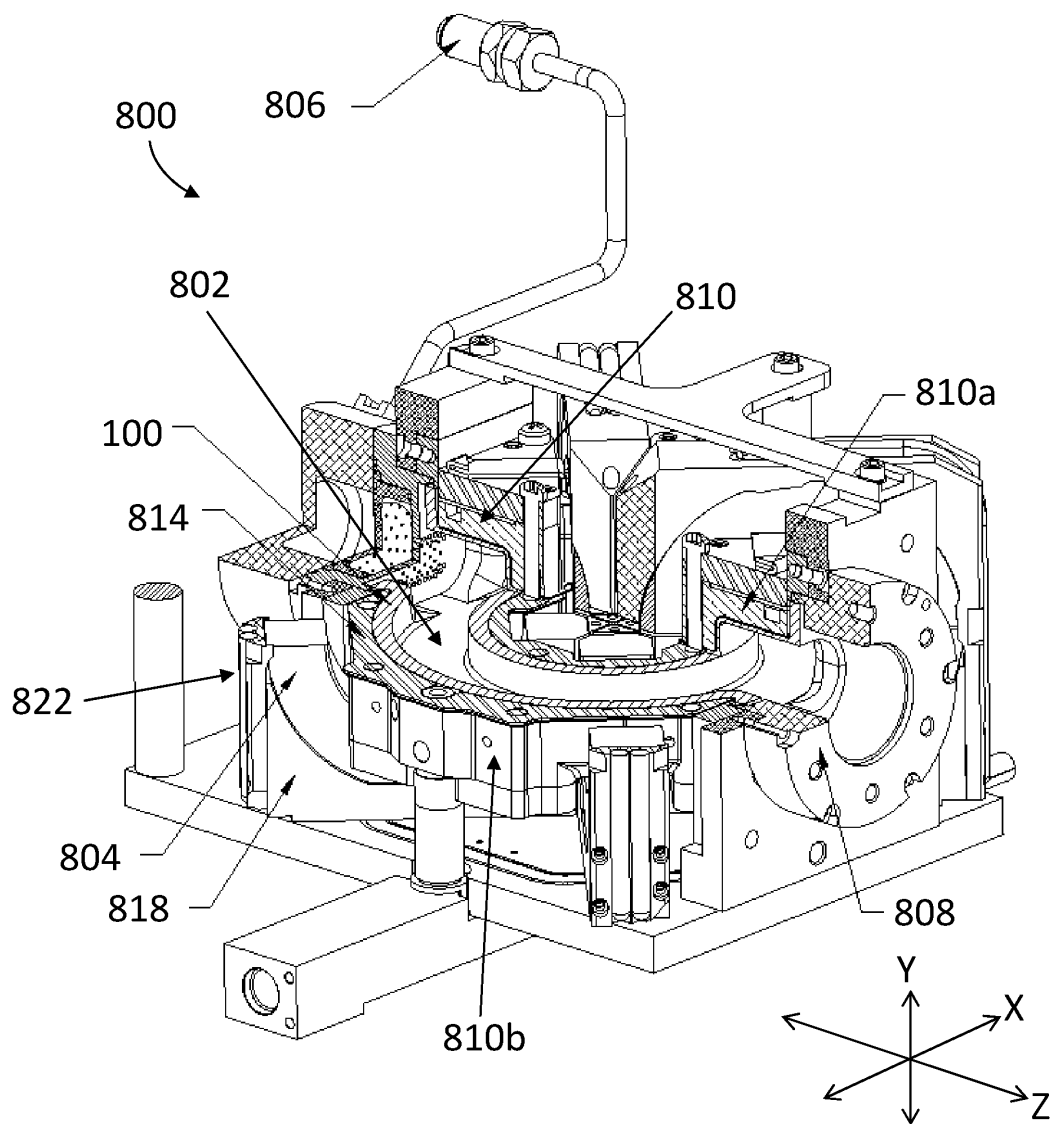


FIG. 8B

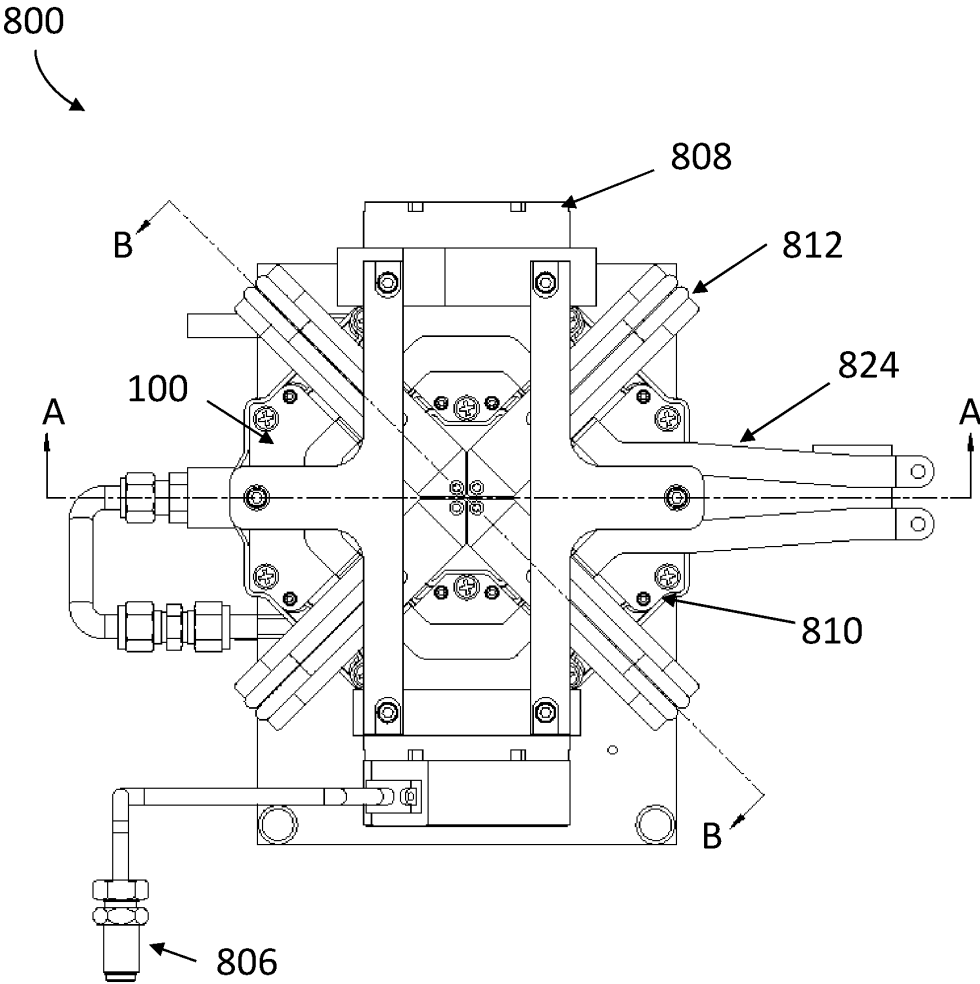
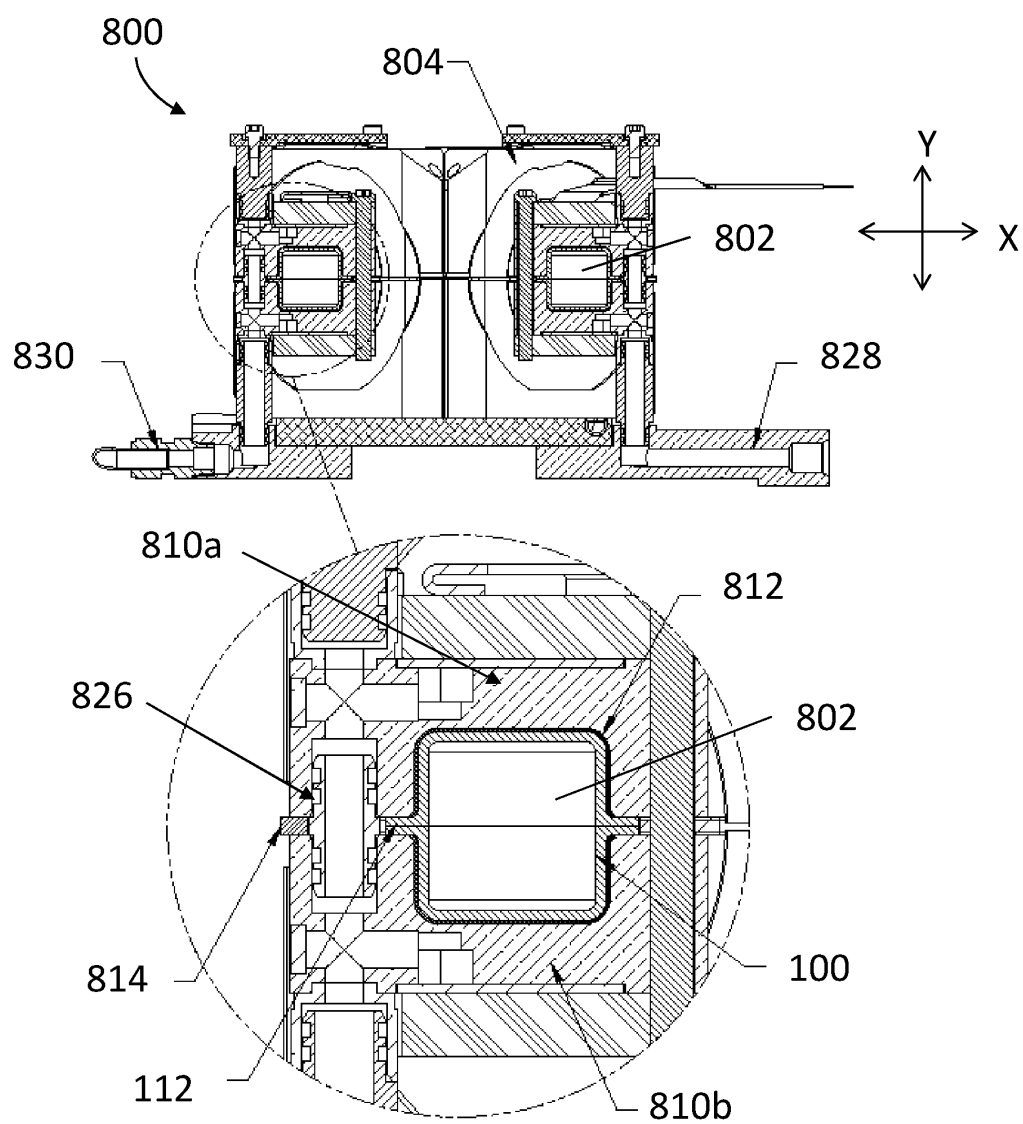
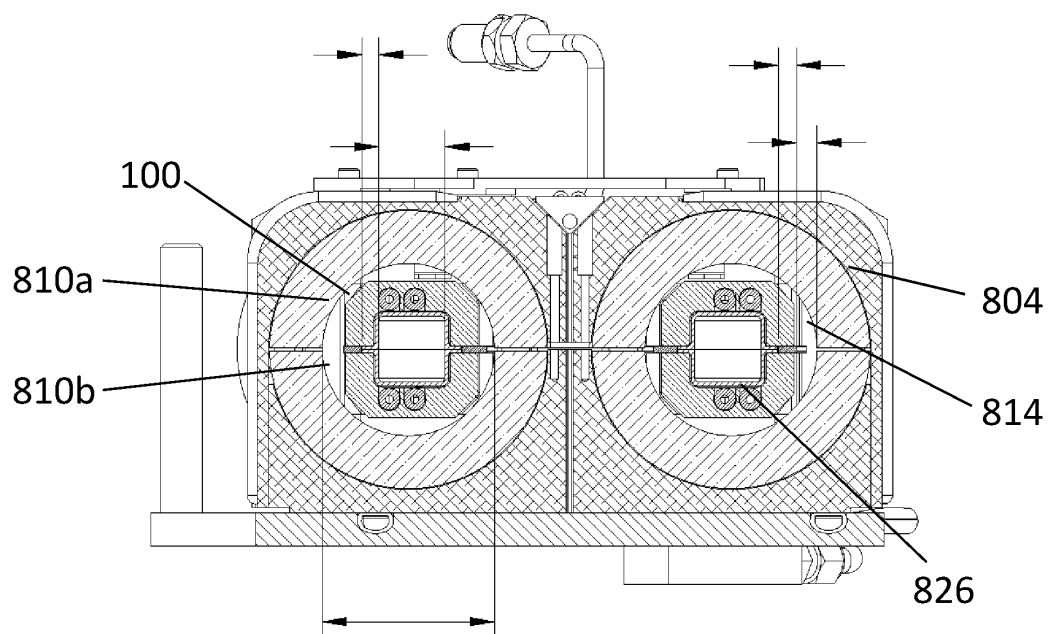


FIG. 8C



SECTION A-A

FIG. 9



SECTION B-B

FIG. 10

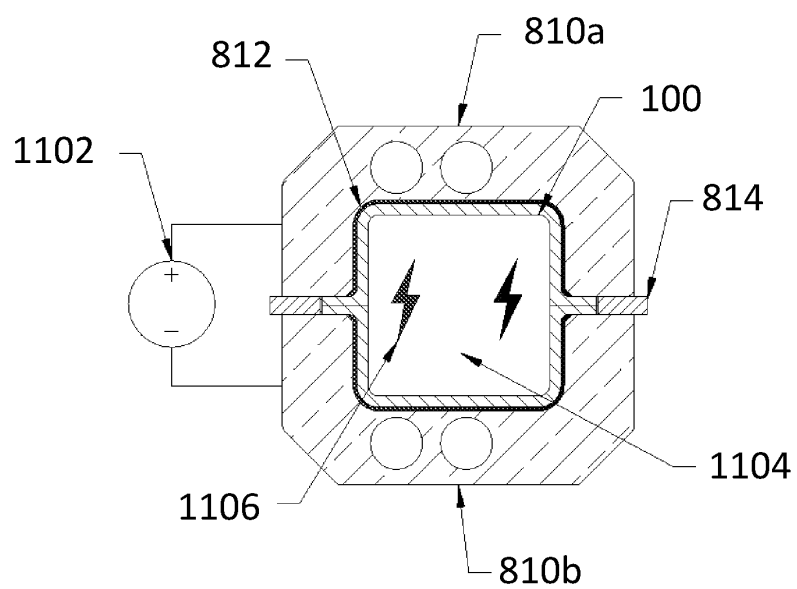


FIG. 11

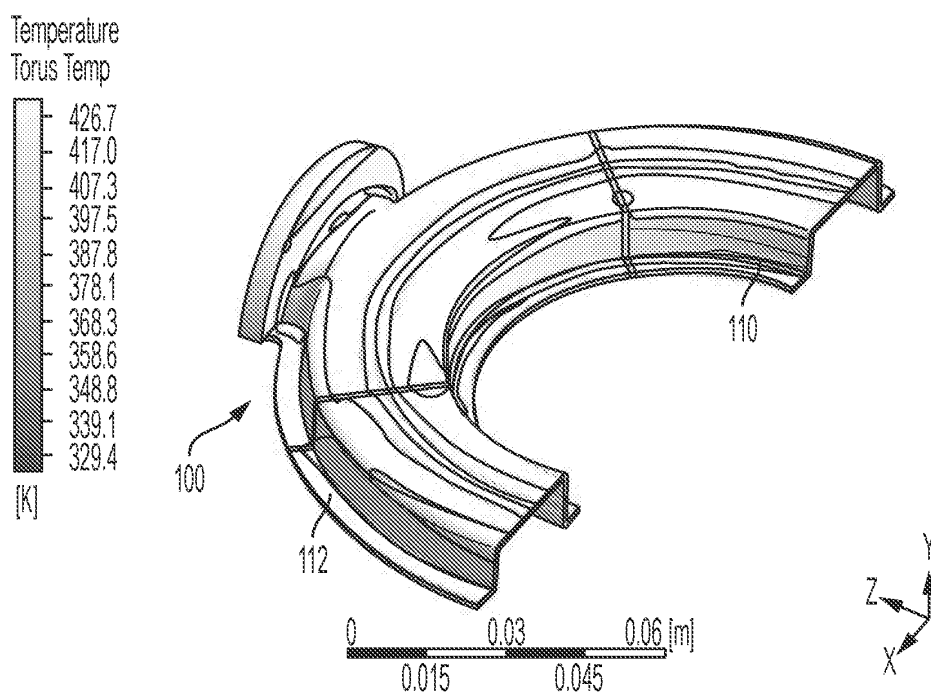


FIG. 12a

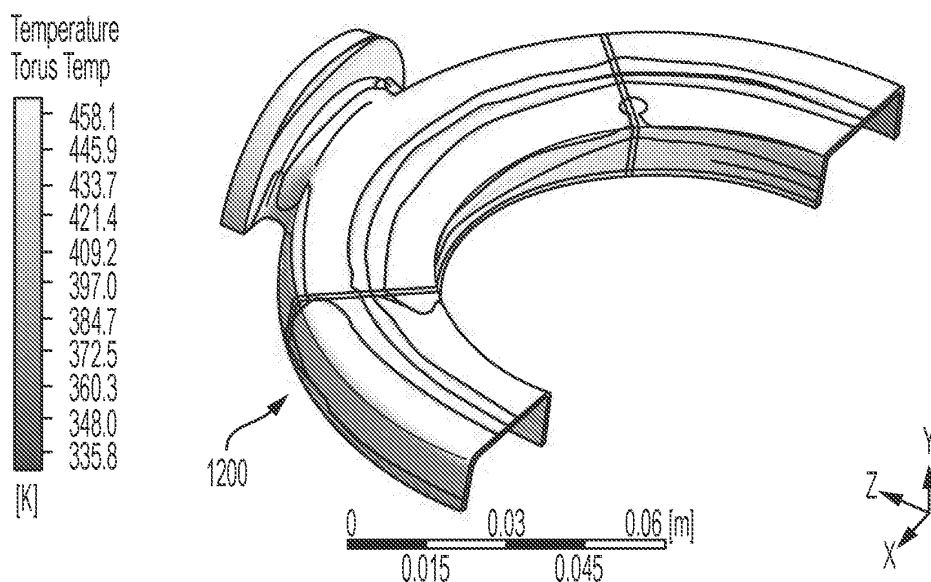


FIG. 12b

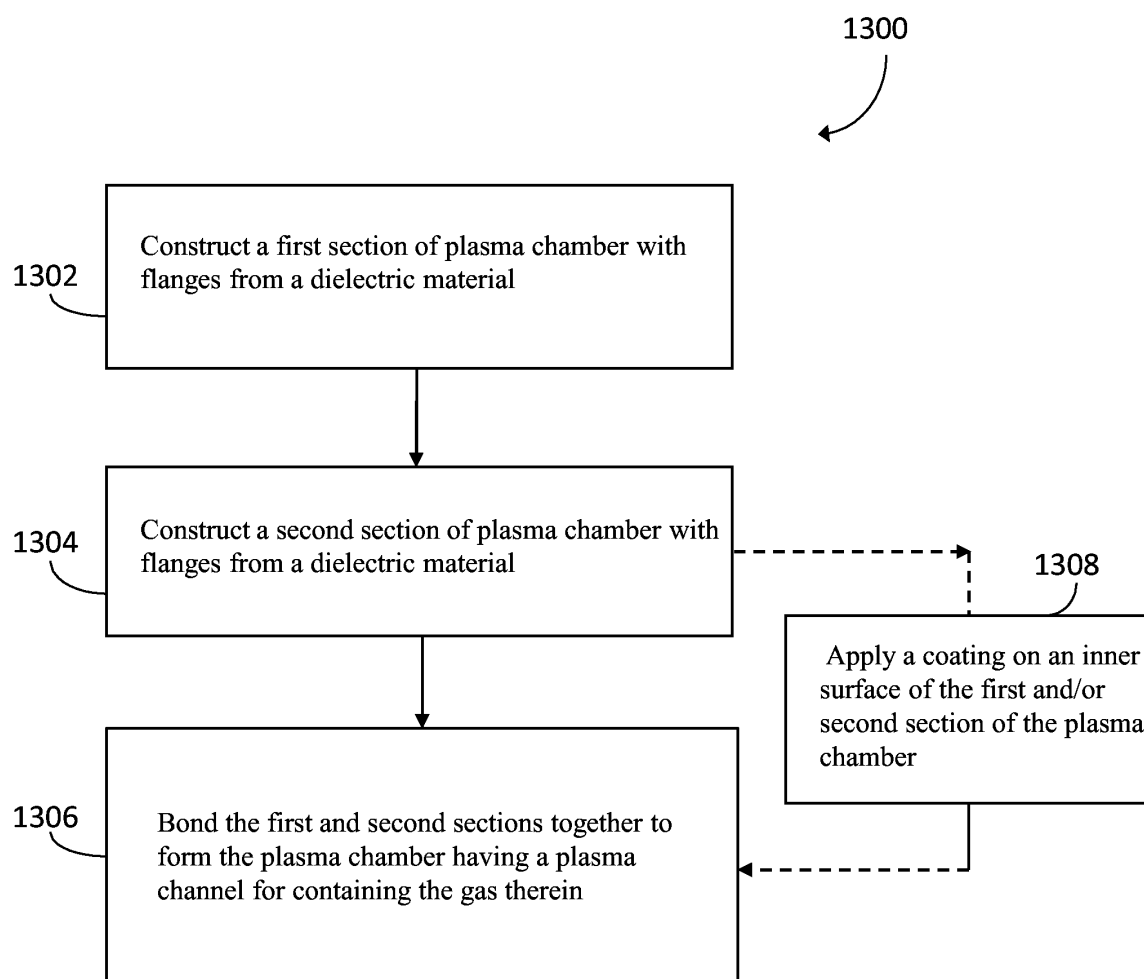


FIG. 13

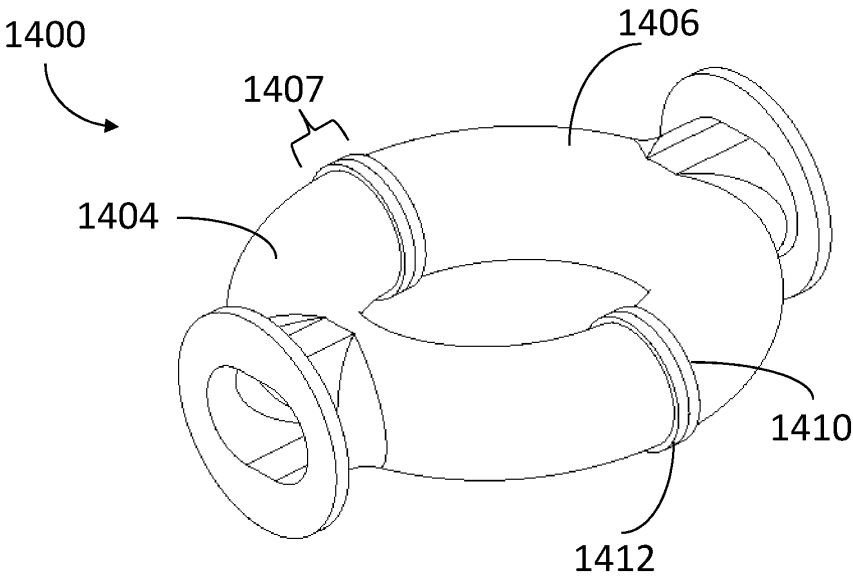


FIG. 14a

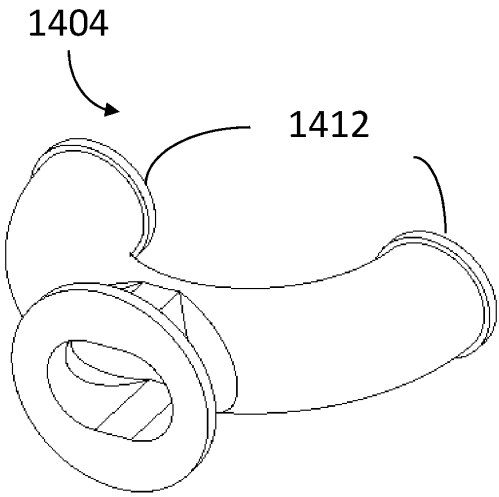


FIG. 14b

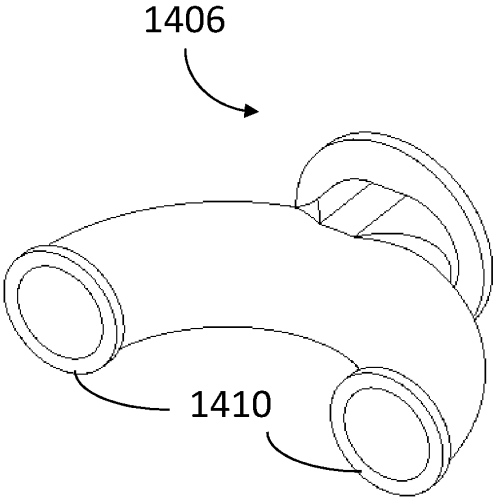


FIG. 14c

Pulsed Operation1 : Remote Plasma on for only Precursor B

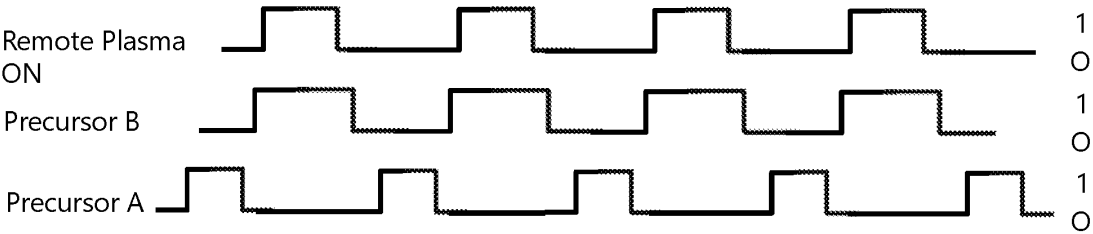


FIG. 15a

Pulsed Operation2 : Remote Plasma on for Precursor A only

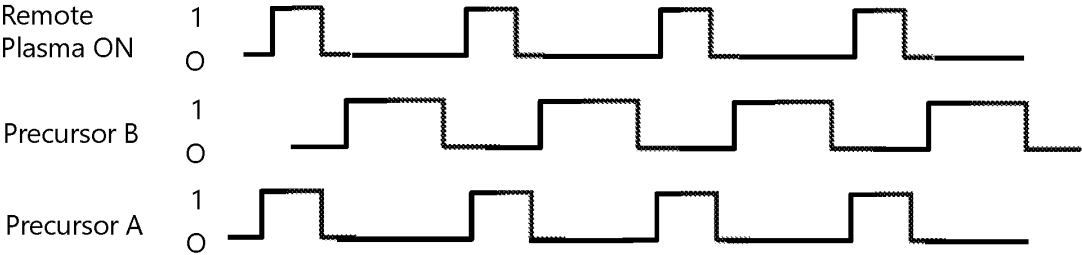


FIG. 15b

Pulsed Operation3 : Remote Plasma on for Both precursors

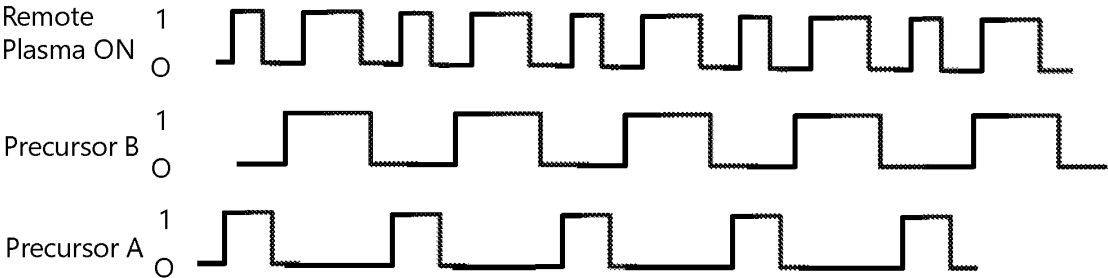


FIG. 15c

Pulsed Operation4 : Remote Plasma on for Precursor B
with a Substrate Bias Applied with Precursor A

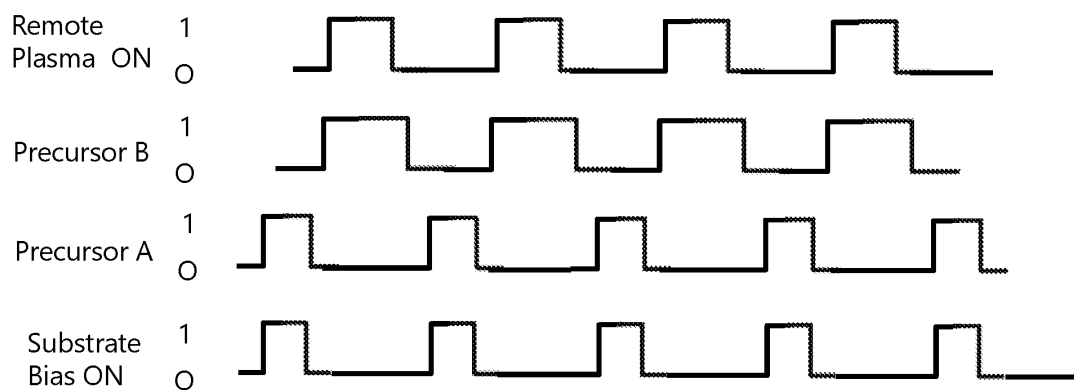


FIG. 15d